



Docket No.: M4065.0227/P227  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Tongbi Jiang et al.

Application No.: 09/652,216

Allowed: April 30, 2004

Filed: August 30, 2000

Art Unit: 2829

For: METHOD AND APPARATUS FOR  
REDUCING SUBSTRATE BIAS VOLTAGE  
DROP

Examiner: E. T. Pert

**SUBMISSION OF FORMAL DRAWINGS**

MS PGPUB Drawings  
Commissioner for Patents  
220 20th Street, S.  
Customer Window  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, VA 22202

Dear Sir:

Submitted herewith is one set (six sheets, six figures) of formal drawings for filing in the above-identified patent application. Figure 4 has been corrected in accordance with the Proposed Drawing Correction filed on March 21, 2002. The Proposed Drawing Correction was approved by the Examiner in the Office Action mailed August 30, 2003 (Paper No. 10). Kindly substitute the enclosed formal drawings for the drawings submitted with the originally filed application.

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Dated: July 26, 2004

Respectfully submitted,

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